

METHODS, COMPLEXES, AND SYSTEMS FOR FORMING
METAL-CONTAINING FILMS ON SEMICONDUCTOR STRUCTURES

Abstract of the Disclosure

A method of forming a film on a substrate using Group IVB, VB, or VIB metal complexes. The methods are particularly suitable for the preparation of semiconductor structures using chemical vapor deposition techniques and systems.

"EXPRESS MAIL" MAILING LABEL NUMBER

EL 776963676 US

DATE OF DEPOSIT

25 May 2001

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